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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): N. HASEGAWA, et al.

Application No.: 10/686,723

Filed: October 17, 2003

For: MANUFACTURING METHOD OF PHOTOMASK AND PHOTOMASK

Expected Group: 1756

Expected Examiner: K. Sagar

SUPPLEMENTAL PRELIMINARY AMENDMENT

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 18, 2003

Sir:

Please amend the above-identified application, prior to examination thereof, as listed below and as set forth on the following pages:

Amendments to the Claims; and

Remarks are included following the amendments.